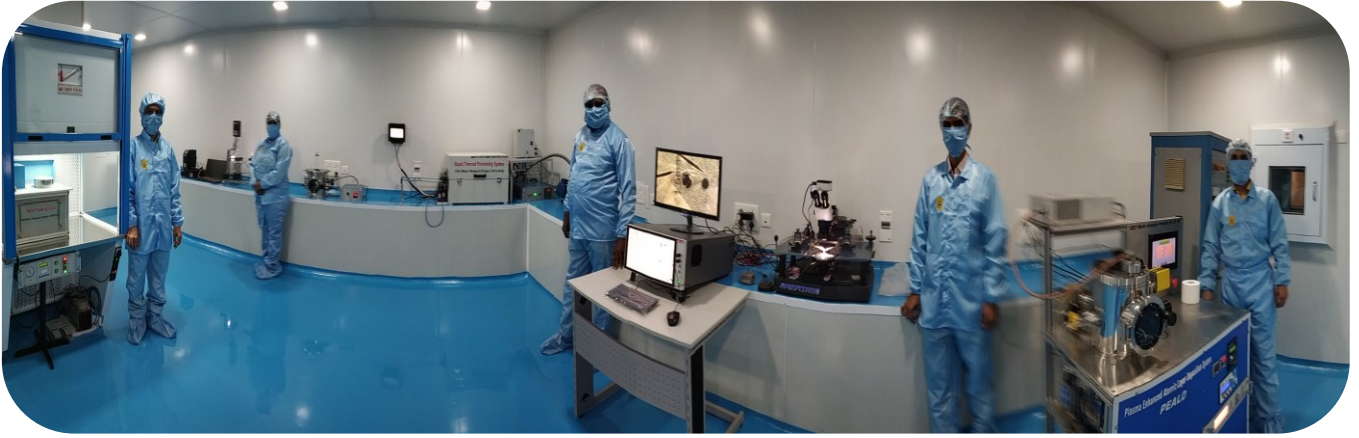


CLASS 10,000 CLEAN ROOM for SEMICONDUCTOR WAFER FABRICATION



“**Class 10,000 clean laboratory for Semiconductor Wafer Fabrication**” having facilities for **semiconductor wafer/devices/chips** fabrication and characterization like **RTP, E-Beam evaporator, Spin coating, Super critical drying setup** etc and **SCS (IV-CV) setup, FTIR, Contact angle measurement, etc.** procured through various government funded projects including the most economic and versatile **Plasma Enhanced Atomic Layer Deposition (PEALD) system** which is main tool for nano layer uniform deposition on the wafer is developed by us, through Nanomission DST funded project.

This cleanroom provides ultra-clean environment to protect testing and fabrication processes from contaminants. This cleanroom feature high-efficiency filters that trap and remove microscopic airborne particles as air changes (60-120 per hour) through the air handling unit by utilizing HEPA filters systems to maintain air cleanliness levels of a maximum of 10,000 particles ($\geq 0.5\mu\text{m}$) per cubic foot. Establishing this unique **class 10,000 clean room laboratory with novel Gate stacks, MOS, MIM and other semiconductor nano devices fabrication and characterization facilities** as step forward towards “**India Semiconductor Mission (ISM)**” of Government of India. This facility is being used by faculty, researchers and master students of the university. Further, it will be made available for the users from **Academia** (other university) and **Industry Personnel** on affordable **access price** and also we are providing the hands on training. Also, we have plans to come up with the **start ups** for “**PEALD system fabrication**” and “**novel uniform nano PEALD coatings**” towards various societal applications in coordination with the university’s KCIIL centre. Enquiries are welcomed.

For more details about lab visit and access to facilities contact:

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P.T.O.



Research Facilities available in Class 10,000 Clean Room Materials and Devices Laboratory for Nanoelectronics (MDLN)

The most economic and versatile indigenously developed **Plasma Enhanced Atomic Layer Deposition (PEALD) system**, **E-Beam evaporator**, **Plasma Treatment Unit (PTU)**, **Rapid Thermal Processing (RTP)**, **Spin coating**, **Super critical drying setup**, etc and **SCS (IV-CV) setup**, **FTIR**, **Contact angle measurement**, etc. including

